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SHEET 1 OF 1

FORM PTO-1449 (SUBSTITUTE)				Attorney Docket No : 2000P1907			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE				Applicant VIRINDER GREWAL ET AL.			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Filing Date January 16, 2002			

  

EXAMINER INITIALS	PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
JL	A	5,948,703	09/99	Shen et al.		
	B	5,874,363	02/99	Hoh et al.		
	C	5,843,239	12/98	Shrotriya		
	D	5,583,737	12/96	Collins et al.		
	E	5,158,644	10/92	Cheung et al.		
	F	5,591,301	01/97	Grewal		
JL	G	5,529,197	06/96	Grewal		
	H					
	I					

  

FOREIGN PATENT DOCUMENT							
DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES   NO		
JL	J	0 814 501 A3	12/97	Europe	X		
	K	0 746 015 A2	12/96	Europe	X		
	L	0 718 868 A2	06/96	Europe	X		
	M						
	N						

  

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
JL	Japanese Patent Abstracts 09045671 A (Yamazaki Shunpei) dated February 14, 1997
JL	"Challenges for 300 mm Plasma Etch System Development", Sanjay Tandon, XP-000974462, March 1998, Semiconductor International, pp. 75-82
EXAMINER	<div style="display: flex; justify-content: space-between;"> <span style="text-align: center;">JL</span> <span>DATE CONSIDERED 10/19/03</span> </div>

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609:  
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